

OFFICIAL**PATENT****IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: RING et al. Examiner: UMEZ ERONINI, I.
Serial No.: 09/864,666 Group Art Unit: 1765
Filed: May 23, 2001 Docket No.: AMDA.497PA
(TT4168)
Title: GAS-ASSISTED ETCH WITH OXYGEN

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence and the papers, as described hereinabove, are being transmitted via facsimile-Formal Entry, to the attention of the Examiner at Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on May 14, 2003.

Facsimile No.: 703-872-9310

By:

Kelly S. Walthney

**RESPONSE TO RESTRICTION
REQUIREMENT WITH CLAIM AMENDMENT**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This communication is in response to the (Restriction Requirement) Office Action dated March 11, 2003. Please enter the following amendment to the above-referenced application and consider the following remarks before further consideration on the merits thereof.

Applicant also submits herewith the following new claims to be entered into this patent application, numbered in accordance with the election of Group I. If necessitated by this Amendment, authority is given to charge/credit Deposit Account 01-0356 (TT4168) requisite fees associated with the filing of the below claims.

In the Claims

Please cancel claims 15-21 of Group II and add the following new claims 22-23:

22. (New) The method of claim 1, further including analyzing the die after supplying sufficient oxygen-containing gas to the die.
23. (New) The method of claim 22, further including obtaining results in response to analyzing the die, and using the obtained results to manufacture additional semiconductor devices.

GROUP 1700

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